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McGuire Woods LLP 1750 Tysons Boulevard Suite 1800 McLean, VA 22102				
EXAMINER				
MCDONALD, RODNEY GLENN				
ART UNIT		PAPER NUMBER		
1753				

DATE MAILED: 11/20/2003

Please find below and/or attached an Office communication concerning this application or proceeding.

## Office Action Summary

**Application No.**

09/781,987

**Applicant(s)**

CHA ET AL.

**Examiner**

Rodney G. McDonald

**Art Unit**

1753

-- The MAILING DATE of this communication appears on the cover sheet with the correspondence address --  
**Period for Reply**

A SHORTENED STATUTORY PERIOD FOR REPLY IS SET TO EXPIRE 3 MONTH(S) FROM THE MAILING DATE OF THIS COMMUNICATION.

- Extensions of time may be available under the provisions of 37 CFR 1.136(a). In no event, however, may a reply be timely filed after SIX (6) MONTHS from the mailing date of this communication.
- If the period for reply specified above is less than thirty (30) days, a reply within the statutory minimum of thirty (30) days will be considered timely.
- If NO period for reply is specified above, the maximum statutory period will apply and will expire SIX (6) MONTHS from the mailing date of this communication.
- Failure to reply within the set or extended period for reply will, by statute, cause the application to become ABANDONED (35 U.S.C. § 133).
- Any reply received by the Office later than three months after the mailing date of this communication, even if timely filed, may reduce any earned patent term adjustment. See 37 CFR 1.704(b).

**Status**

- 1) ☐ Responsive to communication(s) filed on 09 October 2003.
- 2a) ☒ This action is **FINAL**. 2b) ☐ This action is non-final.
- 3) ☐ Since this application is in condition for allowance except for formal matters, prosecution as to the merits is closed in accordance with the practice under *Ex parte Quayle*, 1935 C.D. 11, 453 O.G. 213.

**Disposition of Claims**

- 4) ☒ Claim(s) 18, 30, 31 and 33-35 is/are pending in the application.
- 4a) Of the above claim(s) \_\_\_\_\_ is/are withdrawn from consideration.
- 5) ☐ Claim(s) \_\_\_\_\_ is/are allowed.
- 6) ☒ Claim(s) 18, 30, 31 and 33-35 is/are rejected.
- 7) ☐ Claim(s) \_\_\_\_\_ is/are objected to.
- 8) ☐ Claim(s) \_\_\_\_\_ are subject to restriction and/or election requirement.

**Application Papers**

- 9) ☐ The specification is objected to by the Examiner.
- 10) ☐ The drawing(s) filed on \_\_\_\_\_ is/are: a) ☐ accepted or b) ☐ objected to by the Examiner.  
Applicant may not request that any objection to the drawing(s) be held in abeyance. See 37 CFR 1.85(a).  
Replacement drawing sheet(s) including the correction is required if the drawing(s) is objected to. See 37 CFR 1.121(d).
- 11) ☐ The oath or declaration is objected to by the Examiner. Note the attached Office Action or form PTO-152.

**Priority under 35 U.S.C. §§ 119 and 120**

- 12) ☒ Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).  
a) ☒ All b) ☐ Some \* c) ☐ None of:  
1. ☒ Certified copies of the priority documents have been received.  
2. ☐ Certified copies of the priority documents have been received in Application No. \_\_\_\_\_.  
3. ☐ Copies of the certified copies of the priority documents have been received in this National Stage application from the International Bureau (PCT Rule 17.2(a)).
- \* See the attached detailed Office action for a list of the certified copies not received.
- 13) ☐ Acknowledgment is made of a claim for domestic priority under 35 U.S.C. § 119(e) (to a provisional application) since a specific reference was included in the first sentence of the specification or in an Application Data Sheet. 37 CFR 1.78.  
a) ☐ The translation of the foreign language provisional application has been received.
- 14) ☐ Acknowledgment is made of a claim for domestic priority under 35 U.S.C. §§ 120 and/or 121 since a specific reference was included in the first sentence of the specification or in an Application Data Sheet. 37 CFR 1.78.

**Attachment(s)**

- 1) ☐ Notice of References Cited (PTO-892)
- 2) ☐ Notice of Draftsperson's Patent Drawing Review (PTO-948)
- 3) ☐ Information Disclosure Statement(s) (PTO-1449) Paper No(s) \_\_\_\_\_
- 4) ☐ Interview Summary (PTO-413) Paper No(s). \_\_\_\_\_
- 5) ☐ Notice of Informal Patent Application (PTO-152)
- 6) ☐ Other: \_\_\_\_\_

### **DETAILED ACTION**

#### ***Continued Examination Under 37 CFR 1.114***

A request for continued examination under 37 CFR 1.114, including the fee set forth in 37 CFR 1.17(e), was filed in this application after final rejection. Since this application is eligible for continued examination under 37 CFR 1.114, and the fee set forth in 37 CFR 1.17(e) has been timely paid, the finality of the previous Office action has been withdrawn pursuant to 37 CFR 1.114. Applicant's submission filed on September 3, 2003 has been entered.

#### ***Claim Rejections - 35 USC § 103***

The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negated by the manner in which the invention was made.

This application currently names joint inventors. In considering patentability of the claims under 35 U.S.C. 103(a), the examiner presumes that the subject matter of the various claims was commonly owned at the time any inventions covered therein were made absent any evidence to the contrary. Applicant is advised of the obligation under 37 CFR 1.56 to point out the inventor and invention dates of each claim that was not commonly owned at the time a later invention was made in order for the examiner to consider the applicability of 35 U.S.C. 103(c) and potential 35 U.S.C. 102(e), (f) or (g) prior art under 35 U.S.C. 103(a).

Claims 18 and 30, 31, 34 and 35 are rejected under 35 U.S.C. 103(a) as being unpatentable over Edwards et al. (U.S. Pat. 5,259,881) in view of Kwasnick et al. (U.S. Pat. 5,198,694) and Zhang et al. (U.S. Pat. 5,578,520).

Edwards et al. teach an apparatus for depositing a layer on a substrate as seen in Fig. 1. Edwards et al. teach in Fig. 1 a cluster tool 10 which includes a front transport module 12 and a back transport module 14. The transport modules 12, 14 are provided with vacuum pumps (not shown) to **maintain their internal chambers at a vacuum pressure level suitable for the processing of semiconductor wafers.** (Column 5 lines 41-52)

The transport modules 12, 14 are interconnected by an interconnecting conduit and aligner 16 that joins the interiors of the transport modules 12, 14 to form common transport chamber 18 **at a consistent vacuum level and of a common atmosphere.** Within the transport modules 12, 14 is a wafer transport mechanism or robot arm 20 that rotates about a central axis of the respective module 12, 14 and extends through the ports to load and unload single wafers from the adjoining modules, including the processing modules, handling modules and the other transport module. (Column 6 lines 1-11)

The back transport module 14 has six module connection faces or sides for connection to six adjacent modules. On one of these sides is, in the illustrated embodiment, connected a soft etch module 22 for the cleaning or mild etching preconditioning of the surfaces of wafers. A second of these sides is connected to a **first sputter coating module 24, which will typically perform a sputter coating process to deposit a uniform coating on the surface of the wafer,** usually following the soft etch process in the module 22. Another or third side is connected to another processing module, a rapid thermal processing (RTP) module 26, for treating the wafer quickly with high temperatures of, for example 1000.degree. C., to anneal or smooth a **previously deposited coating, such as a metal coating deposited by a sputter coating process in the sputtering module 24.** A forth side is connected to another processing module, for

example a sputtering module 28, that may be a sputter etching module or another sputter coating module. **A fifth face is connected to another processing module 30 that may be, for example, a chemical vapor deposition (CVD) module.** The types of modules and the processes performed therein may be any process suitable to be performed on wafers in conjunction with the other processes being performed by the cluster tool. The sixth face of the transport module is connected to the aligner 16. (Column 6 lines 12-39)

The load-locks 32, 24 each have an access door through which a standard cassette of, for example 25, wafers are held in a rack, usually made of a plastic material such as polypropylene. The racks are loaded and unloaded either manually or by robot through a load-lock access door 41 into each of the load-locks 32, 34. **The access doors 41, when closed, seal internal load-lock chambers within the load-locks so that they may be pumped to the vacuum environment of the transport chamber 18 to permit entry of the wafers, transferred individually by the transport arm 20, into the transport chamber 18 and to the other modules of the cluster tool 10.** When the transport arm 20 returns wafers to the load-locks 32, 34, the load-lock is vented to the external environment. Except when the load-locks are at the vacuum pressure level of the transport chamber 18, the gate valve between the transport chamber 18 and respective load-lock 32, 34 is closed. (Column 6 lines 51-68)

**Connected to the other two faces of the entry transport module 12 are two preferably identical batch preheating, degassing or desorption modules 42, 44.** Each of these modules is equipped to receive, hold and preprocess a plurality of wafers simultaneously, preferably any number up to the quantity held in a full wafer cassette handled by the load-locks 32, 34. (Column 7 lines 1-7)

The batch preheating modules 42, 44 according to certain embodiments of the present invention, will be described in relation to the module 42. Referring to FIG. 2, the preheating module 42 includes a pressure tight housing 50 enclosing a preheating chamber 52. The housing has a hole 53 therein to which a high vacuum pump 54 (removed in this figure; see FIG. 3) is connected to maintain the chamber 52 at a high vacuum, typically equal to that of the transport chamber 18. The module 42 is also conventionally provided with a second pump (not shown) for lowering the pressure from atmospheric pressure to within the operating range of the pump 54, and with a vent port (not shown) for returning the pressure within the chamber 52 to that of the atmosphere. The housing 50 also has therein, on the front thereof, a rectangular port 56 to which the module is connected to a gate valve 58 (FIG. 3) of the front transport module 12. (Column 7 lines 12-25).

The differences between Edwards et al. and the present claims is that utilizing the chambers for forming layers of a thin film transistor is not discussed, the layers of a thin film transistor is not discussed and depositing the layers in a series of chambers is not discussed.

Kwasnick et al. teach in Fig. 1 a cross-section view of a substrate 12 on which a plurality of thin-film transistors are to be fabricated. *A layer of gate metallization 18 is disposed across the entire upper surface of the illustrated portion of the substrate 12. (Column 4 lines 30-34) Following patterning of the gate metallization 18, a gate dielectric layer 28 is deposited across the entire upper surface of the substrate and gate metal. The gate dielectric is preferably 0.1 to 0.5 microns thick. Next, a layer 30 of intrinsic amorphous silicon from 0.1 to 0.5 microns thick is deposited on the gate dielectric layer without breaking vacuum in the deposition chamber. Next, a layer 32 of n<sup>+</sup> amorphous silicon from 0.01 to 0.1 microns thick is deposited*

*on top of the intrinsic silicon 30, again without breaking the vacuum in the deposition chamber.* The structure at the end of these steps is illustrated in Fig. 3. (Column 4 lines 52-66)

The structure illustrated in Fig. 4 is ready for the deposition of the source/drain metallization for this thin-film transistor. In accordance with the invention, *a first relatively thin layer 34 (0.01 to 0.1 microns thick) of a first conductor is deposited directly on the n+ amorphous silicon. The first conductor is preferably chromium but may also be nichrome, tantalum or other appropriate metals which make good ohmic contact to n+ amorphous silicon.* (Column 5 lines 13-21)

The motivation for utilizing the chambers for depositing the particular layers is that it allows for the deposition of a thin film transistor. (Column 4 lines 30-34)

Zhang et al. teach a forming a semiconductor device utilizing a multi-chamber system. (See Abstract) Zhang et al. teach a multi-chamber system for fabricating TFTs on a substrate shown in Fig. 3. The multi-chamber system utilized in this embodiment is a modification of the system shown in Fig. 2 (To be discussed). While the chamber are serially connected in one line in the system of Fig. 2, a plurality of chambers are connected with one another through one common chamber in the present embodiment, as referred to hereinbefore. (Column 7 lines 27-33)

In Fig. 2 the apparatus comprises a serial arrangement for forming the TFT. (Column 6 lines 6-13)

The motivation for continuing to treat the substrate under vacuum in a serially arranged apparatus is that it allows avoiding neutralization of dangling bonds. (Column 6 lines 49-55)

Therefore, it would have been obvious to one of ordinary skill in the art at the time the invention was made to have modified Edwards et al. by depositing in the chambers the layers required for forming a thin film transistor as taught by Kwasnick et al. And to have arranged chambers in serial as taught by Zhang et al. because it allows for the production of a thin film transistor and for the avoiding neutralization of dangling bonds.

**Claims 18 and 30, 31 and 33-35 are rejected under 35 U.S.C. 103(a) as being unpatentable over Turner et al. (U.S. Pat. 5,512,320) in view of Kwasnick et al. (U.S. Pat. 5,198,694).**

Turner et al. teach a method for depositing sequential thin films on glass substrates by single substrate deposition comprising loading a batch of substrates into a load lock chamber and evacuating the chamber, transferring the substrates to a batch heating chamber for heating the substrates to elevated temperatures; transferring the glass substrates singly to one or more single substrate processing chambers, and sequentially transferring the substrates back to the load lock chamber where they are batch cooled. (See Abstract)

Liquid crystal cells for active matrix TV and computer monitors are made of two glass plates sandwiching a layer of liquid crystal material between them. The glass plates are made conductive with a thin conductive film on the inside faces of the plates so that a source of power may be connected to them for changing the orientation of the liquid crystal molecules. As the need for larger and more sophisticated cells that allow separate addressing of different areas of the **liquid crystal cell has progressed**, as for active matrix TV where up to 1,000,000 or more



different areas or pixels need to be separately addressed, **the use of thin film transistors for this application has come into widespread use. Thin film transistors comprise a patterned metal gate** over which is deposited a gate dielectric layer and a conductive layer, such as amorphous silicon. **Subsequently applied layers, as of doped amorphous silicon, etch stopper silicon nitride, silicon oxide, metal contact layers and the like, are also required to be deposited over the amorphous silicon thin film. Many of these films are deposited by CVD** in order to obtain high quality films. (Column 1 lines 15-34)

A vacuum system 10 for processing large glass substrates in accordance with the invention is shown in FIG. 1. The vacuum system 10, referring now to FIG. 1, comprises a central transfer chamber 12 to which are connected **two load lock/cooling chambers 14A and 14B**, each for transferring the glass substrates to be processed into the system 10. The load lock/cooling chambers 14A and 14B have a closable opening comprising a load door 16A and 16B respectively on its outside wall for transfer of glass substrates to be processed into the vacuum system 10 from the atmosphere. (Column 3 lines 19-28)

The cassettes 17 in the load lock/cooling chambers 14 are mounted on an elevator assembly (not shown) to raise and lower the cassettes 17 incrementally the height of one shelf. To load chamber 14A, the load door 16A is opened and one glass substrate is placed on a shelf in the cassette 17. The elevator assembly raises the cassette 17 by the height of one shelf so that an empty shelf is opposite the load door 16A. Another substrate is placed on that shelf and so forth until all of the shelves of the cassette 17 are filled. **At that point the load door 16A is closed and the chamber 14A is evacuated to the desired pressure in the vacuum system 10.** (Column 4 lines 1-11)

A slit valve 20A on the inside wall of the load lock/cooling chamber 14A adjacent to the transfer chamber 12 is then opened. **The glass substrates are transferred by means of a robot 22 in the transfer chamber 12 to a heating chamber 28.** (Column 4 lines 12-16)

After the last glass substrate is loaded into the heat cassette 29, the first glass substrate has reached processing temperature. **After a heated glass substrate is transferred by means of the robot 22 to one of the single substrate processing chambers 40, 42, 44 and 46, it is always replaced with a cold one to be heated. The processing chambers 40, 42, 44 and 46 are adapted to deposit one or more thin layers onto the glass substrates.** Each of the film chambers 40, 42, 44 and 46 are also fitted on their inner walls 40a, 42a, 44a and 46a respectively with a slit valve 41, 43, 45 and 47 respectively for isolation of the process gases. More than one process chamber can be operational at the same time. (Column 4 lines 46-53)

Although the above system is described using a plurality of film deposition chambers, **other single substrate processing chambers can be included or substituted**, including etch chambers, **physical vapor deposition chambers**, preclean chambers and the like. (Column 5 lines 4-8)

The arrows 48, 49 and 50 respectively show the direction of transfer for one possible sequence; arrow 48 shows the direction of **transfer from the load lock/cooling chamber 14B to the heating chamber 28**; arrow 49 shows the direction of transfer of a substrate from the **heating chamber 28 to a CVD chamber 40**; and the arrow 50 shows the direction of transfer of a substrate from the CVD chamber 40 back to the load lock/cooling chamber 14B until the load lock is fully exchanged; then when the chamber 14B is venting to atmosphere, load lock chamber

14A is available to the vacuum robot so that continuous processing is provided. (Column 5 lines 21-31)

**For the manufacture of thin film transistors** onto large glass substrates, the average time for loading a glass substrate into and unloading it out of a load lock/cooling chamber is about 15 seconds for each operation; (Column 6 lines 18-21).

The differences between Turner et al. and the present claims is that the order and thickness of the layers are not discussed and depositing the layers in a series of chambers is not discussed.

Kwasnick et al. is discussed above and teach the order and the thickness of layers for a thin film transistor. (See Kwasnick et al. discussed above)

The motivation for depositing the layers in a certain order and with a certain thickness is that it allows for depositing a thin film transistor. (See Kwasnick et al. discussed above)

Zhang et al. is discussed above and teach arranging chambers in serial to form a thin film transistor. (See Zhang et al. discussed above)

The motivation for continuing to treat the substrate under vacuum in a serially arranged apparatus is that it allows avoiding neutralization of dangling bonds. (Zhang et al. discussed above)

Therefore, it would have been obvious to one of ordinary skill in the art at the time the invention was made to have modified Turner et al. by depositing the layers in a certain order and with a certain thickness as taught by Kwasnick et al. and to have serially arranged vacuum chambers as taught by Zhang et al. because it allows for forming a thin film transistor and for avoiding neutralization of dangling bonds.

***Response to Arguments***

Applicant's arguments filed September 3, 2003 have been fully considered but they are not persuasive.

***RESPONSE TO THE ARGUMENTS OF THE 35 U.S.C. 103 REJECTIONS OF CLAIMS 18, 30, 31, AND 35 AS OBVIOUS OVER EDWARDS ET AL. IN VIEW OF KWASNICK ET AL. AND ZHANG ET AL.:***

In response to the argument that Edwards does not disclose the specifically claimed functions of each chamber, it is argued that Kwasnick suggest the claimed deposition functions that can be performed in Edwards CVD, sputtering chambers, etc. (See Edwards et al. and Kwasnick discussed above)

In response to the argument that Kwasnick does not teach transferring the substrate from the deposition chamber to the sputter chamber in a vacuum, it is argued that Edwards et al. recognize that the deposition chambers including sputter chamber are connected in vacuum and that the substrate can be transferred in vacuum to the different chambers in the cluster tool. Kwasnick teach the deposition functions when making a TFT. (See Edwards et al. and Kwasnick discussed above)

In response to the argument that Zhang does not disclose the substrate transferred from the deposition chamber to the sputter chamber in a vacuum, it is argued that Edwards recognize that the deposition chambers including the sputter chamber are connected in vacuum and the substrate can be transferred in vacuum to the different chambers in the cluster tool. (See Edwards discussed above)

***RESPONSE TO THE ARGUMENTS OF THE 35 U.S.C. 103 REJECTIONS OF CLAIMS  
18, 30, 31 AND 33-35 AS OBVIOUS OVER TURNER ET AL. IN VIEW OF KWASNICK:***

In response to the argument that Turner fails to disclose any kind of vacuum passage for transferring a substrate, on which an amorphous silicon layer is formed, in a vacuum deposition chamber to the sputter chamber, it is argued that Turner require that the system 10 be under vacuum when transferring the substrates to the different chambers. Turner refers to the robot being a *vacuum* robot. Thus Turner suggest transferring the substrate from various chambers to sputter chambers. (See Turner discussed above)

In response to the argument that Kwasnick does not disclose a deposition chamber depositing a doped amorphous silicon layer or a sputter chamber depositing a metal layer on the doped amorphous silicon layer, it is argued that Kwasnick teach depositing a doped amorphous silicon layer and a metal layer. (See Kwasnick et al. discussed above) Turner suggests the chambers. (See Turner discussed above)

In response to the argument that Kwasnick fails to disclose the substrate transferred from the deposition chamber to the sputter chamber in vacuum, it is argued that Turner teach the chambers required for deposition and transferring the substrate under vacuum. (See Turner discussed above)

***Conclusion***

All claims are drawn to the same invention claimed in the application prior to the entry of the submission under 37 CFR 1.114 and could have been finally rejected on the grounds and art of record in the next Office action if they had been entered in the application prior to entry under 37 CFR 1.114. Accordingly, **THIS ACTION IS MADE FINAL** even though it is a first action

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after the filing of a request for continued examination and the submission under 37 CFR 1.114. See MPEP § 706.07(b). Applicant is reminded of the extension of time policy as set forth in 37 CFR 1.136(a).

A shortened statutory period for reply to this final action is set to expire THREE MONTHS from the mailing date of this action. In the event a first reply is filed within TWO MONTHS of the mailing date of this final action and the advisory action is not mailed until after the end of the THREE-MONTH shortened statutory period, then the shortened statutory period will expire on the date the advisory action is mailed, and any extension fee pursuant to 37 CFR 1.136(a) will be calculated from the mailing date of the advisory action. In no event, however, will the statutory period for reply expire later than SIX MONTHS from the mailing date of this final action.

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Any inquiry concerning this communication or earlier communications from the examiner should be directed to Rodney G. McDonald whose telephone number is 703-308-3807. The examiner can normally be reached on M- Th with Every other Friday off.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Nam X. Nguyen can be reached on 703-308-3322. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9310.

Any inquiry of a general nature or relating to the status of this application or proceeding should be directed to the receptionist whose telephone number is 703-308-0661.



Rodney G. McDonald  
Primary Examiner Art Unit 1753

RM  
November 10, 2003